

## Supplementary Material

### Device simulation of layer dependence on 10-nm-gate MoS<sub>2</sub> transistors

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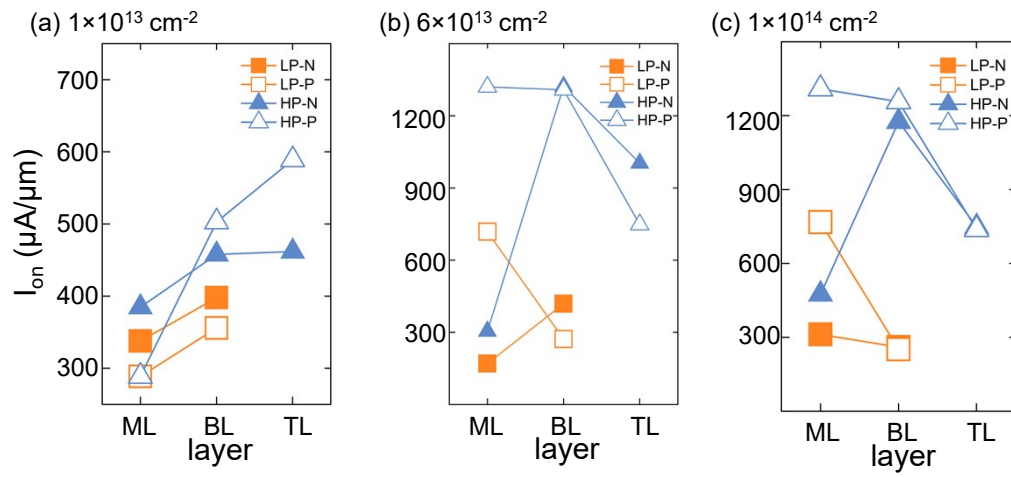
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**Table S1.** Device performances for  $n$ - and  $p$ -type 10-nm-gate MoS<sub>2</sub> MOSFETs with 1 to 3 layers under various doping concentrations at  $V_{dd} = 0.5$  V. The IRDS LP and HP targets for “5am eq” node (2023 version) are given for comparison. Here,  $N_{s/d}$ : source/drain doping concentration;  $I_{off}$ : off-state current;  $I_{on}$ : on-state current; SS: subthreshold swing;  $g_m$ : transconductance;  $C_g$ : intrinsic gate capacitance (excluding parasitic capacitances);  $\tau$ : delay time; and PDP: power dissipation.

type	layer	$N_{s/d}$ (cm <sup>-2</sup> )	$I_{off}$ ( $\mu$ A/ $\mu$ m)	$I_{on}$ ( $\mu$ A/ $\mu$ m)	SS (mV/dec)	$g_m$ (mS/ $\mu$ m)	$C_g$ (fF/ $\mu$ m)	$\tau$ (ps)	PDP (fJ/ $\mu$ m)
$n$ -type	ML	$6 \times 10^{13}$	$10^{-4}$	170	58	1.03	0.26	2.25	0.19
	ML	$1 \times 10^{14}$	$10^{-4}$	312	54	1.97	0.24	1.17	0.18
	BL	$1 \times 10^{13}$	$10^{-4}$	398	56	2.20	0.21	0.80	0.16
	BL	$1 \times 10^{14}$	$10^{-4}$	261	57	5.72	0.29	1.65	0.21
$p$ -type	ML	$1 \times 10^{13}$	$10^{-4}$	289	52	1.40	0.19	0.99	0.14
	ML	$6 \times 10^{13}$	$10^{-4}$	718	46	6.83	0.17	0.37	0.13
	BL	$6 \times 10^{13}$	$10^{-4}$	272	64	7.45	0.22	1.20	0.16
	BL	$1 \times 10^{14}$	$10^{-4}$	252	66	8.26	0.25	1.46	0.18
IRDS LP (“5am eq”)			$10^{-4}$	587	65	—	0.37	1.13	0.40
$n$ -type	ML	$1 \times 10^{13}$	$10^{-2}$	385	55	1.98	0.28	1.09	0.21
	ML	$6 \times 10^{13}$	$10^{-2}$	305	58	1.03	0.79	3.91	0.60
	BL	$1 \times 10^{13}$	$10^{-2}$	458	56	2.20	0.22	0.72	0.16
	BL	$1 \times 10^{14}$	$10^{-2}$	1176	57	5.72	0.34	0.44	0.26
	TL	$1 \times 10^{13}$	$10^{-2}$	462	68	2.16	0.25	0.82	0.19
	TL	$1 \times 10^{14}$	$10^{-2}$	749	71	6.43	0.36	0.72	0.27
$p$ -type	ML	$1 \times 10^{13}$	$10^{-2}$	289	52	1.40	0.15	0.75	0.11
	ML	$1 \times 10^{14}$	$10^{-2}$	1309	46	8.20	0.26	0.30	0.20
	BL	$1 \times 10^{13}$	$10^{-2}$	503	63	2.50	0.16	0.48	0.12
	BL	$1 \times 10^{14}$	$10^{-2}$	1257	66	8.26	0.29	0.35	0.22
	TL	$1 \times 10^{13}$	$10^{-2}$	589	72	2.97	0.18	0.46	0.14
	TL	$1 \times 10^{14}$	$10^{-2}$	738	76	6.75	0.32	0.65	0.24
IRDS HP (“5am eq”)			$10^{-2}$	790	70	—	0.37	0.84	0.40



**Figure S1.** Layer-dependent  $I_{on}$  of the  $n$ - and  $p$ -type 10-nm-gate  $MoS_2$  MOSFETs under doping concentrations of (a)  $1 \times 10^{13}$ , (b)  $6 \times 10^{13}$ , and (c)  $1 \times 10^{14} \text{ cm}^{-2}$  for LP and HP applications.